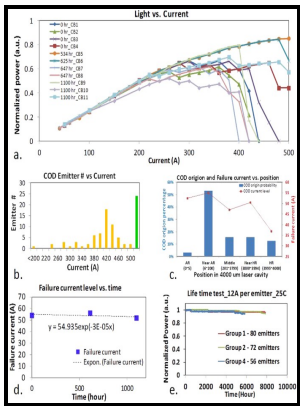
Quantum-well laser array packaging - nanoscale packaging techniques

McGraw-Hill - US5259049A



Description: -
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High power lasers
Nanoscience
Quantum wells
Microelectronic packagingQuantum-well laser array packaging - nanoscale packaging techniques
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Nanolaser arrays: toward application

Mark Facility Manager's Maintenance Handbook Description: An Updated Guide to Establishing Cutting-Edge Operationsand Maintenance Procedures for Today's Complex Facilities An essential on-the-job resource, Facility Manager's. It is important to note, however, that besides bonding and antibonding modes, various other types of supermodes can also be observed in coupled nanolaser systems.

New Products

Pulsed laser welding has proven to be the preferred bonding method that best facilitates the automated fiber alignment and bonding process of optoelectronic devices. Further, each different area of the active region or each waveguide may be electrically pumped by a separate, individually addressable, current injection means.

ShieldSquare

Applications include use in gyroscopes, high-voltage current sensors, communications systems, and polarization-sensitive components.

Quantum

Further applications of the self-aligned coupling method in combination with a tapered external waveguide are conceivable.

Quantum

This compressive strain of the active region causes a reduction in the valence band effective mass, resulting in closer symmetry of the conduction and valence bonds, and thereby enhancing the transition probability and increasing the quantum conversion efficiency.

Photonics & Optoelectronics

DRC 1987, Postdeadline paper, Santa Barbara, June 1987. In their work, Marconi et al.

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The chirality of the beams can also be reversed by applying an external magnetic field. The resulting mirror groove 121 with transferred ridge structure 122. In a next step, or sequence of steps, a mask 119 for etching the mirror groove is formed.

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